



Prof. Hyo-Chang Lee

Korea Aerospace University, Korea

Education & Career

- 2012. 08 Ph.D., Department of Electrical Engineering @ Hanyang University (Korea)
- 2012 ~ 2015 Lecture Professor/Research Professor/Research Fellow @ Hanyang University (Korea)
- 2013 ~ 2013 Visiting Researcher @ Princeton Plasma Physics Laboratory, Princeton University (USA)
- 2015 ~ 2016 Senior Researcher @ Etch Technology Team, Memory division, Samsung Electronics (Korea)
- 2016 ~ 2023 Principal Research Scientist @ Korea Research Institute of Standards and Science (Korea)
- 2023 ~ now Professor @ School of Electronics and Computer Engineering, Korea Aerospace University

Representative Academic Activity & Honor

- Prime Minister Award (Korea Invention Exhibition, 2021)
- Professional Examiner (Korea Intellectual Property Tribunal, 2021~now)
- IEEE Senior Member (2018)
- Hershkowitz Early Career Award (IOP, 2020)
- Distinguished Research Scientist (KRISS, 2020~2022)

Publication

- SCI papers: more than 90 (also, several review papers including Appl. Phys. Rev. 5, 011108 (2018))
- Patents: more than 30

Research Interest

- Plasma sources, Plasma diagnostics, Plasma Material-Processing, Plasma Applications